

re Application of:

Gaillard, et al.

Serial No.: 10/789,209

Confirmation No.: 9101

Filed: February 27, 2004

For: Method of Decreasing the
K Value in SIOC Layer
Deposited by Chemical
Vapor Deposition

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**Group Art Unit: 2818**

Examiner: David Nhu

**MAIL STOP ISSUE FEE**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

Dear Sir:

**CERTIFICATE OF MAILING**

37 CFR 1.8

I hereby certify that this correspondence is being deposited on 6/3, 2005 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Issue Fee, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6/3/05

Date \_\_\_\_\_

Kiss & Zuck

Signature

## AMENDMENT AFTER ALLOWANCE

Following mailing of a Notice of Allowance on May 9, 2005, Applicants request entry of the following amendments. **Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 6 of this paper.